## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Attn: APPLICATION BRANCH

Hiroshi SOTOZAKI et al.

Attorney Docket No. 2004 0208

Serial No. NEW

:

Filed February 10, 2004

:

METHOD AND APPARATUS FOR POLISHING A SUBSTRATE (Rule 1.53(b) Continuation of Serial No. 10/283,154, Filed October 30, 2002, which is a divisional of Serial No. 09/434,482, filed November 5, 1999)

THE COMMISSIONER IS AUTHORIZED TO CHARGE ANY DEFICIENCY IN THE FEES FOR THIS PAPER TO DEPOSIT ACCOUNT NO. 23-0975

## **CLAIM OF PRIORITY UNDER 35 USC 119**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Applicants in the above-entitled application hereby claim the date of priority under the International Convention of Japanese Patent Application No. 10-316522, filed November 6, 1998, Japanese Patent Application No. 11-138705, filed May 19, 1999 and Japanese Patent Application No. 11-236776, filed August 24, 1999, as acknowledged in the Declaration of this application.

Certified copies of said Japanese Patent Application are of record in grand-parent application Serial No. 09/434,482, filed November 5, 1999.

Respectfully submitted,

( )

Hiroshi SOTOZAKI et al.

A Complete

Registration No. 46,500 Attorney for Applicants

JMG/edg Washington, D.C. 20006-1021 Telephone (202) 721-8200 Facsimile (202) 721-8250 February 10, 2004